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The invention relates to the semiconductor instrument engineering and may be utilized for the optical signals detection and processing, transmitted through the fiber optical communication lines, through the Earth atmosphere or through other optical media.

The summary of the invention consists in the fact that the selective photodiode is manufactured on the heterostructure base, comprising a substrate n-InP with the length of the forbidden zone E_{g0} , the active layer $In_x1Ga_{1-x1}As_{y1}P_{1-y1}$ with E_{g1} , the frontal layer p^+ $In_x2Ga_{1-x2}As_{y2}P_{1-y2}$ with E_{g2} and anti-reflection coating on the face with E_{g3} , to which $E_{g1} < E_{g2} < E_{g0} < E_{g3}$, characterized by the fact that the p-n transition is formed into the frontal layer in the close proximity to the heteroboundary with the active layer, which is executed with the i- conductance type, and the thickness of the frontal layer is more than the diffusion length of the unbasic charge carriers, generated on the photodiode face.

The technical result of the invention consists in the fact that at the reverse displacement the space charge layer is dilated into the active layer, dividing the generated charge carriers into it.

Claims: 1

Fig.: 4